

AMENDMENTS TO THE CLAIMS:

This listing of claims will replace all prior versions, and listings, of claims in the application:

Claims 1-26 cancelled.

27. (New) A method of applying inscriptions in relief to substrates made of plastic, comprising:

ejecting drops of fluidized plastic and controlling deposit of said plastic drops in a single operation, only at those places that form the relief inscription, at a sufficient temperature to insure a physical-chemical bond with the material constituting the substrate; and cooling the deposited material.

28. (New) An inscription method according to claim 27 wherein the step of ejecting drops only at those places that form the relief inscription is obtained by moving ejector nozzles in a first direction ^{and} moving the substrate in a transverse direction to said first direction and controlling the activation of the ejector nozzles in relation to the places and to the inscription.

29. (New) An inscription method according to claim 27 wherein each substrate is a magnetic card.

30. (New) An inscription method according to claim 27 wherein each substrate is a smart card.

31. (New) An inscription method according to claim 27 wherein each substrate is a badge.

32. (New) An inscription method according to claim 27 including vibrating the ejector nozzles, controlling the synchronization and frequency of the vibrating ejector nozzles supplied with fluidized plastic material from a reservoir to produce the deposition of drops of fluidized

BEST AVAILABLE COPY

✓ plastic material at the places necessary for a number of deposited drops to form an alpha numeric character or logo or an increased thickness or any other form of raised area.

33. (New) An inscription method according to claim 27 wherein the relief inscription constitutes a bar code.

34. (New) An inscription method according to claim 27 wherein the relief inscription constitutes codes carrying information concerning the substrate or the user of the substrate.

35. (New) An inscription method according to claim 27 including controlling the ejection of the drops as a function of the speed at which the substrates pass in registration with the ends of ejector nozzles.

36. (New) An inscription method according to claim 27 wherein said ejector nozzles are in the form of tubes.

37. (New) An inscription method according to claim 27 including moving each substrate made of plastic in registration with a print station equipped with a number of nozzles, ejecting drops of plastic material at variable viscosity from said nozzles to form relief points on the substrate, controlling the positioning of the nozzles and the drops in a direction transverse to that of the movement of the substrates, and controlling the duration of the ejection of each drop as a function of both the speed of travel of the substrates and data constituting the inscription.

38. (New) An inscription method according to claim 27 including cooling the deposited material at a location remote from the location of the deposition of the plastic drops.

39. (New) An inscription method according to claim 27 including controlling the transfer speed of the substrates in registration with an inscription station and each of the ejector nozzles of the fluidized plastic material.

40. (New) A method of applying inscriptions in relief to substrates made of plastic comprising:

ejecting drops of fluidized plastic through ejector nozzles and controlling deposit of said plastic drops in a single operation only at those places that form the relief inscription at a sufficient temperature to insure a physical-chemical bond with the material constituting the substrate, moving the substrate past the ejector nozzles, positioning the drops in a direction transverse to that of the movement of the substrates by controlling the ejector nozzles, and controlling the ejection duration of each drop as a function of both the speed of travel of the substrates and the data constituting the inscription, and cooling the deposited material.

41. (New) An inscription method according to claim 40 wherein the step of ejecting drops only at those places that form the relief inscription is obtained by moving ejector nozzles in a first direction and moving the substrate in a transverse direction to said first direction and controlling the activation of the ejector nozzles in relation to the places and to the inscription.

42. (New) An inscription method according to claim 40 wherein each substrate is a magnetic card.

43. (New) An inscription method according to claim 40 wherein each substrate is a smart card.

44. (New) An inscription method according to claim 40 wherein each substrate is a badge.

45. (New) An inscription method according to claim 40 including vibrating the ejector nozzles, controlling the synchronization and frequency of the vibrating ejector nozzles supplied with fluidized plastic material from a reservoir to produce the deposition of drops of fluidized

plastic material at the places necessary for a number of deposited drops to form an alpha numeric character or logo or increased thickness of any other form of raised area.

46. (New) An inscription method according to claim 40 wherein the relief inscription constitutes a bar code.

47. (New) An inscription method according to claim 40 wherein the relief inscription constitutes codes carrying information concerning the substrate or the user of the substrate.

48. (New) An inscription method according to claim 40 including controlling the ejection of the drops as a function of the speed at which the substrates pass in registration with the ejector nozzles.

49. (New) An inscription method according to claim 40 wherein said ejector nozzles are in the form of tubes.

50. (New) An inscription method according to claim 40 including moving each substrate made of plastic in registration with a print station equipped with a number of nozzles, ejecting drops of plastic material of variable viscosity from said nozzles at a sufficient temperature to insure a physical-chemical bond with the material comprising the substrate, said drops forming relief points on the substrate, controlling the ejector nozzles to control the positioning of the drops in a direction transverse to that of the movement of the substrates, and controlling the ejection duration of each drop as a function of both the speed of travel of the substrates and the data constituting the inscription.

51. (New) An inscription method according to claim 50 including cooling the deposited material at a location remote from the location of the deposition of the plastic drops.

52. (New) An method according to claim 50 wherein the step in which a plastic material of variable viscosity is deposited in a single operation is made by the deposition station and

PEYTOUR, Norbert
Appl. No. 09/986,648
March 9, 2005

including controlling the transfer speed of the substrates in front of the deposition station, and the rate of deposition of the fluidized plastic material through each of the ejector nozzles.